

U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICELIST OF REFERENCES CITED BY APPLICANT(S)  
(Use several sheets if necessary)APPLICANTS  
YASUHIRO SHIMADA *EPAC*FILING DATE  
June 14, 2001

NOV 01 2001

GROUP  
2881

## U.S. PATENT DOCUMENTS

*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
S.K.		5,439,777	8/8/95	Kawada et al.	430	270	
S.K.		5,959,957	9/28/99	Ikeda et al.	369	127	
S.K.		5,343,460	8/30/94	Miyazaki et al.	369	126	
S.K.		6,156,215	12/5/00	Shimada et al.	216	11	
S.K.		6,201,226	3/13/01	Shimada et al.	250	201.3	
S.K.		5,677,978	10/14/97	Lewis et al.	385	147	
S.K.		5,959,957	9/28/99	Ikeda et al.	369	127	

## FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
S.K.		4-90152	3/24/92	Japan			Abstract
S.K.		11-64350	3/5/99	Japan			Abstract
S.K.		10-293134	11/4/98	Japan			Abstract
S.K.		11-66650	3/9/99	Japan			Abstract
S.K.		2-98849	4/11/90	Japan			Abstract

## OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)

S.K.	R.C. Reddick et al., "New form of scanning optical microscopy", Physical Review B, The American Physical Society, vol. 39, no. 1, January 1, 1989, pp. 767-770.
S.K.	G. Binning et al., "Surface Studies by Scanning Tunneling Microscopy", Physical Review Letters, The American Physical Society, vol. 49, July 5, 1982, pp. 57-61.
S.K.	U. Dürig et al., "Near-field optical-scanning microscopy", Journal of Applied Physics, 1986 American Institute of Physics, vol. 59, no. 10, 15 May 1986, pp. 3318-3327.

EXAMINER *SK*DATE CONSIDERED *5/30/02*

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Sheet 1 of 1